Search Notes		

Application No.	Applicant(s)	
10/604,244	TAI ET AL.	
Examiner	Art Unit	
Toan M Le	2863	

SEARCHED			
Class	Subclass	Date	Examiner
702	84	8/31/2004	TL
700	109	8/31/2004	TL
			:

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
702	84	9/1/2004	TL
700	109	9/1/2004	TL

SEARCH NOT (INCLUDING SEARCH)
	DATE	EXMR
Wafer In-line Yield Prediction	9/1/2004	TL
Wafer Yield Analysis; Statistical; Regression; Sample	9/1/2004	TL
Wafer Quality Control Analysis; Parameter; Lot; Sample	8/31/2004	TL
Quality Control, Sample, Parameter, Search, Database, Analyzing, Correlating, Wafer	8/31/2004	TL